



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Seung-un KIM, et al.

Art Unit:

1763

Serial No.

10/084,198

Examiner:

Sylvia MacArthur

Filed:

February 28, 2002

Confirmation No.

4922

For:

APPARATUS AND METHOD FOR SUPPLYING CHEMICALS IN CHEMICAL MECHANICAL

POLISHING SYSTEMS

## AMENDMENT UNDER 37 C.F.R. §1.312

Commissioner for Patents Alexandria, VA 22313-1450 MAIL STOP: ISSUE FEE

Sir:

## **INTRODUCTORY COMMENT(S)**

In response to the Examiner's Amendment presented in the Notice of Allowability mailed December 15, 2003, please amend the application identified above as follows: